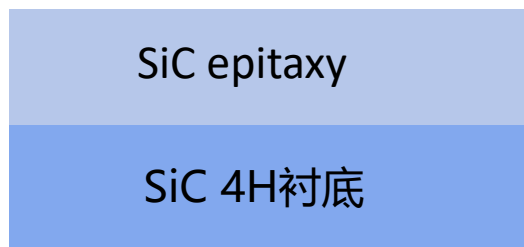


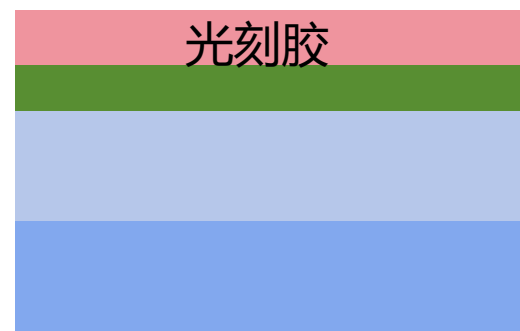
一、采用离子注入的流片过程



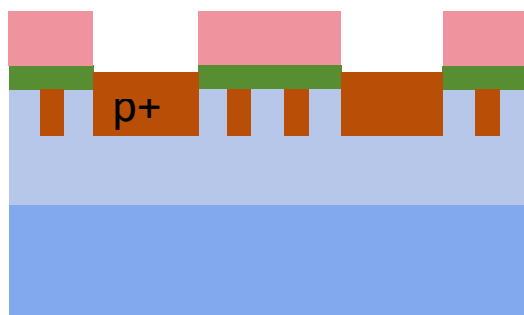
①全外延结构



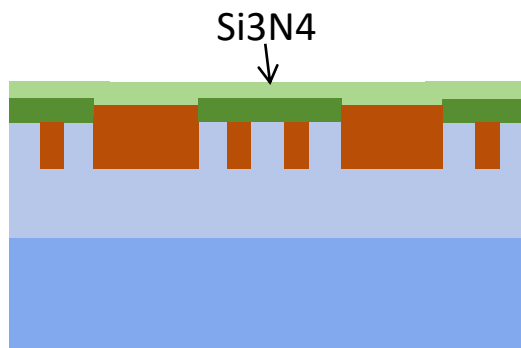
②生长氧化层



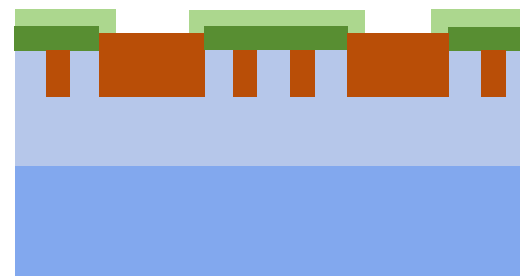
③涂胶与光刻



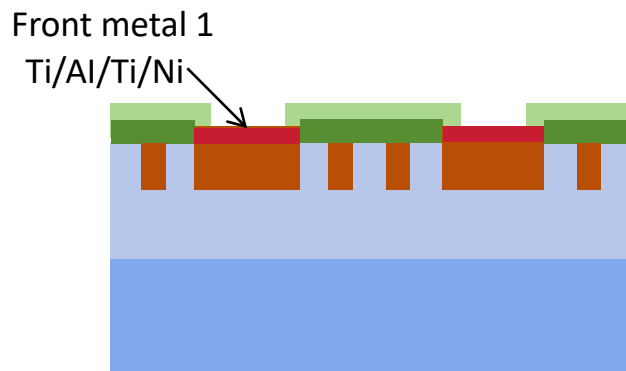
④离子注入



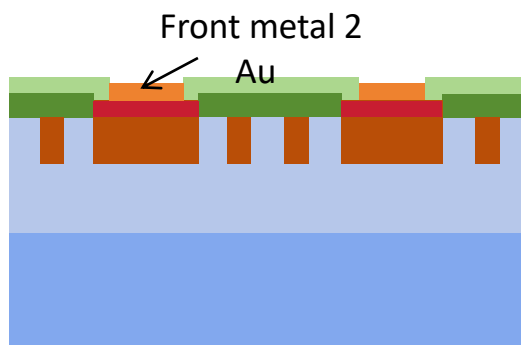
⑤去胶与高温退火



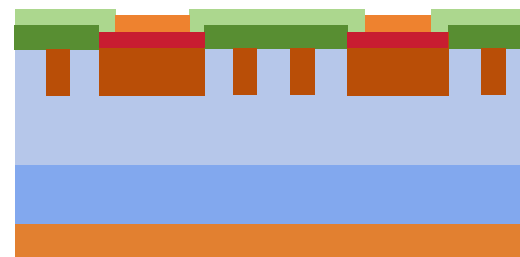
⑥沉积钝化层



⑦第一次金属化



⑧第二次金属化



⑨衬底减薄+背底金属沉积

二、光刻板的绘制

